

PATENT
97-CT-174IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
RAFFAELE ZAMBRANO
Serial No.: 09/191,743
Filed: November 13, 1998
For: IN-SITU DEPOSITION AND
DOPING PROCESS FOR POLY-
CRYSTALLINE SILICON LAYERS
AND THE RESULTING DEVICE

Group Art Unit: 2823

Examiner: M. Estrada

FAX COPY RECEIVED
AUG 12 2002
TECHNOLOGY CENTER 2800

AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated December 28, 2001, the due date for response to which has been extended to June 28, 2002 by the enclosed petition for extension of time, in connection with the above-identified application, please enter and consider the following amendment and remarks.

I hereby certify that this correspondence
is being deposited with the United States
Postal Service with sufficient postage as
first class mail in an envelope addressed
to: Commissioner for Patents,

Washington, D.C. 20231, on 6/28/02
Date of Deposit

Stephen Bongini
Applicant, Assignee, or Representative

Signature

Dated 6/28/02